


**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
DOCKET NO.
10020/29701

SERIAL NO.
10/690,704

APPLICANT
SHTEIN et al.

FILING DATE
October 23, 2003

GROUP
1762

U. S. PATENT DOCUMENTS

| EXAMINER INITIAL | DOCUMENT NUMBER | PUBLICATION DATE | NAME | CLASS | SUBCLASS | FILING DATE |
|---------------------|--------------------|---------------------|------|-------|----------|----------------|
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FOREIGN PATENT DOCUMENTS

| EXAMINER INITIAL | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION | |
|---------------------|--------------------|------------------|---------|-------|----------|-------------|----|
| | | | | | | Yes | No |
| | WO 02/087787 | November 7, 2002 | PCT | | | X | |
| | WO 03/020999 | March 13, 2003 | PCT | | | X | |
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NON PATENT LITERATURE DOCUMENTS

| EXAMINER INITIAL | | AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC. |
|---------------------|--|--|
| | | Shtein et al., "Direct mask-free patterning of molecular organic semiconductors using organic vapor jet printing", Journal of Applied Physics, Volume 96, Number 8, pp. 4500-4507, October 15, 2004. |
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EXAMINER /David Tuocoy/

DATE CONSIDERED 03/22/2010

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.